

OPTICAL INVESTIGATIONS AND OPTICAL CONSTANTS OF NANO SILVER OXIDE PREPARED BY PLD METHOD

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ABSTRACT: High purity Ag₂O (silver Oxide) thin films with high transparent conductive properties will be deposited successfully by reactive pulsed laser deposition method. The Optical property shows a high transparency reached to about (90) % and found to decreases sharply with decreasing of laser fluency. The optical energy band gap of the deposited film at the optimum prepared condition is around 3.46eV. The prepared samples were analyzed using the UV-visible and photoluminescence. The results give an indication that the deposited films crystallize to be more regular in the distribution of atoms, and the energy band gap approaches 3.47 eV when the laser fluency decrease. The optical investigations and constant of the energy band gap, the refractive index, and the extinction coefficient were also elaborated.

Keywords: Silver Oxide, Optical properties, Optical constants, PLD technique.

I. INTRODUCTION

One of the most important p-type semiconductors with a direct band gap around 1.4 eV is the Silver oxide (Ag₂O) [21-23] thin films of this material have some unique physical properties that have attracted much interest.[1-4]. They have been used widely in the batteries electric pole and in the photography [5]. And in the SERS (surface-enhanced Raman spectroscopy) and in a surface-plasmon (SP) source. Many methods can be used to prepare and deposit the AgOx, such as the (CBD) chem.-bath dep. [3, 6], thermal evaporation and (RMS) reactive magnetron sputtering, exposing the films of silver to atomic oxygen environment, and Pulsed Laser Deposition techniques [7, 8].

The reactive Pulsed Laser Deposition using a pure silver targets while feeding it with oxygen gas as a catalyst to increase the interaction between pure silver atoms and gas to obtained and controlling to the oxygen composition ratio and to allowed to use a low energy of lasers for deposition [9,10]. The optical properties of AgOx have been studied previously [11], the correlation between the microstructural features and the process parameters during deposition has not yet been well established. In this work, we studied the optical properties of Deposited AgOx thin films on the glass substrate. The additional analysis by X-ray diffraction results [12, 13].

In this paper, we present the PLD as a technique to deposit Ag₂O over substrate of glass. The research continued to study and analyze the effect of Laser fluency on the growth mechanism of the material and, thereafter, transmission, reflection, bandgap and refractive index are presented and discussed deeply.

II. MATERIAL AND METHODS

Undoped Ag₂O thin films were prepared and deposited on a cleaned slide of glass as a substrate using tattoo removal Nd: YAG laser. The pulse duration of the Q-switched Nd: YAG laser is 7 ns (FWHM) with wavelength= 1.064 nm, the laser beam was focused through a lens with a focal length=10 cm spotted on a silver target (99.999% provided from Fluka com.). The targets spin at a rate of one cycle per minute. The energy density of a pulse laser at the target surface was maintained within the range 43 and 57 mJ/cm². All prepared thin films were created by 50 laser shots at the temperature of the substrate is 150 C°. The thicknesses of the deposited thin film were tested using the scanning optical reflectometer. The optical properties such as the

transmittance of the prepared films were investigated at spectral range (300–1000) nm using UV-VIS Shimadzu double beam spectrophotometer.

The value of the incident energy of photon was studied as a function of (λ) depending on the formula [14-16]

$$E_g(eV) = 1240/\lambda(nm) \quad (1)$$

where λ is wavelength. The energy gaps are dependence on the value of the absorption coefficient (α) and the excitation of the transition could be described depending on the Tauc formulas [17, 18]

$$(ahv) = B(hv - E_g)^r \quad (2)$$

where the B is a constant inversely proportional to amorphous, r is a constant = 2, 3, etc... depending on the raw used materials and the type of the optical transition ahv . If the straight part of the plot of the $(ahv)^{1/r}$ against (hv) is extrapolated to $(ahv)^{1/r} = 0$, the intercept gives the energy gap value. The value of the absorption coefficient (α) for all wavelengths was examined by [19, 20]

$$\alpha = 2.303(A/t) \quad (3)$$

where A is absorbance and t is transmittance.

with A is the absorption and t is the thickness of nanophotonic films. Equation (4) relates the absorption coefficient (α) with the excitation ratio (K) [21, 22]:

$$K = \alpha \lambda / 4\pi \quad (4)$$

All other constants such as refractive index (n), the ϵ_r and ϵ_i which they relate to the real and imaginary parts of the dielectric constants, the conductivity (σ) are used to calculated from equation (5) [23, 24]:

$$n = \{ [4R / (R-1)] - K^2 \}^{1/2} - [(R+1) / (R-1)] \quad (5)$$

Note that R represents the reflectance which can be found from $(R = 1 - T - A)$, or it can be obtained from equation (6) [25, 26]:

$$n = n_s \left(\frac{1 + \sqrt{R}}{1 - \sqrt{R}} \right)^{1/2} \quad (6)$$

where n_s denotes to the substrate refractive index. It is an important to mention that the refractive index of the glass substrate is considered to be 1.51, [27, 28]:

III. RESULT AND DISCUSSION

UV-VIS optical spectra for the transmission of the thin film deposited and prepared under different laser fluency conditions are present. The optical properties of deposited Ag₂O₃ at two different laser fluency could be shown in Figure (1). In general, a decrease in the optical transmission as a function of wavelength could be recognized with increasing with laser fluency due to the increase in laser ablation efficiency and the amount of the ablated material and finally this effect on the thickness of thin films and the distribution of ablated materials on the substrates. Implying that the deposited films at the low value of laser energy have a much smaller size. The exciton peak shift with the particle size values is due to the quantum confinement attributed to inducing the energy band gap variation. The spectral characteristic of the semiconductor has been shown to vary with the effects of quantization. The values of energy band gap (ΔE) vary with the radius values of the particles (d).

$$\Delta E = \left(\frac{h}{2me^*}\right) \left(\frac{\pi^2}{d^2}\right) \quad (7)$$

where ΔE (energy shift or optical band gap shift with respects to bulk band gap value (3.35 eV) and d is the size of the particle, h the constant of Planck's and me^* is the electron reduced mass thus with the decrease in the value of the particle size.

Indeed the increase in the value of laser fluency means transfer more of the laser energy and indicate to ablating the larger amount of the raw materials. It was observed that the increase of the Fluency of the laser produce the plume of the plasma become denser and could become more intense and this gives an indication that the large particles will be produced due to the two fact, the first fact is due to the longer time of growth and the other fact as a result of the high probability of clustering. The alteration of the $(\alpha hv)^2$ value with the values of the photon energy (hv) is present in figure (2), the value of the optical band gap (E_g) of Ag₂O₃ NPs are calculated from the extrapolating of linear part of $(\alpha hv)^2$ as a function of photon energy (hv) plot on x-axis. The values of the optical band gap (E_g) are found to be varied from (3.47-3.45) eV with the effect of laser fluency. These values of the optical energy band gap have as lightly redshift as the laser fluency will be increased (increase in particle size), this result agrees with other work [29, 30].

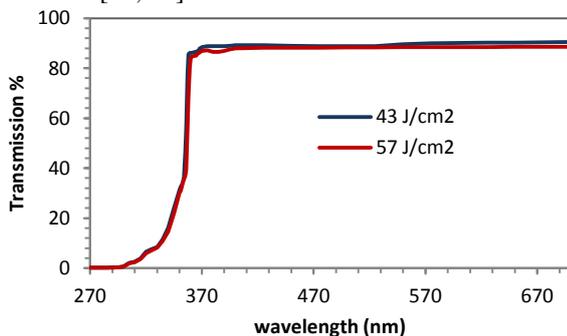


Fig 1 optical transmission spectra of Ag₂O₃ at two different laser fluency

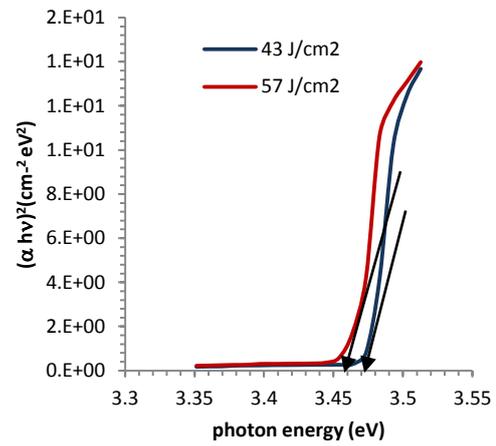


Figure (2), the optical band gap (E_g) of Ag₂O₃

The reflectance (R %) of Ag₂O₃ NPs was testing by using the double-beam UV-vis instrument. Fig. 3 was present the reflectance spectra of the Ag₂O₃ NPs films as a function of (λ) range of 300-700 nm. It's clearly observed that optical reflection increased with the increasing of the Laser fluency and this increasing as a result due to the fact that when the beam of the light effects on the thin layer of the film the light beam is slightly reflected and then transmitted, depending on the energy of the incident photon, the thickness of the films and the size of the deposit particles since the deposited material consists of the charged particles, the bounds and the loose electrons, and the ionic elements, etc.

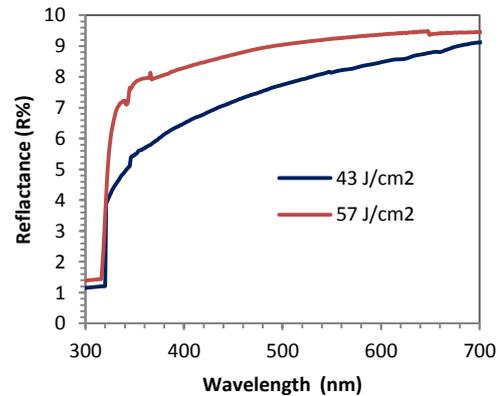


Figure (3), the reflectance of Ag₂O₃

The value of (n) was calculated using the reflectance spectrum values in the range of 300-700 nm. There is a tangible change in the refractive index (n) value in the visible range; according to estimates and found to be about 1.24 – 1.31 at 330 nm as present in Fig. 4 and is tabulated in Table 1. The increasing in the particle size values results in overall causes decreasing of the refractive index; this due to the result of decreasing the transmission value as the thickness increases. The value of the (n) changes a bit after 310 nm to 700 nm wavelength. It could be showed that the n decreases with the laser fluency, this behavior may be attributed to a decline of the film thickness as present in table 1, which resulting in low reflection, the elevated value of the refractive index is good for an optoelectronic device. The extinction coefficient K is a very important physical parameter related to microscopic atomic interactions. The extinction coefficient is shown in Fig. 5 as a function

of photon energy, has high value at higher Laser fluency.

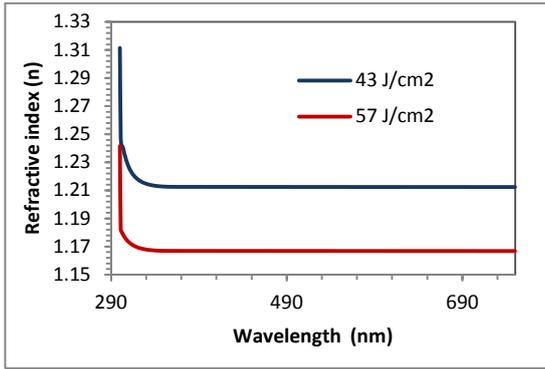


Figure (4), the refractive index of Ag₂O₃

It shows that the extinction coefficient is high in the region of the high energy photon, and it will decrease with decreasing of the photon energy. The stronger absorbing medium present high extinction coefficient [49]. The loss of the energy of the electromagnetic radiation out of the medium is examined using the extinction coefficient value of a special substance. The value of extinction coefficient is inversely associated with the value of the spectra of the transmittance [50], therefore the low value of T% gives a high value of extinction coefficient.

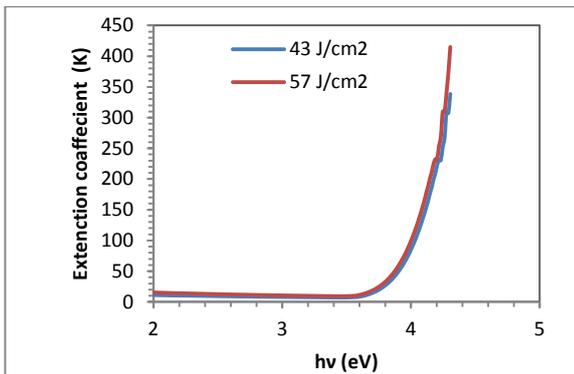


Figure (5), the extinction coefficient of Ag₂O₃

Table 1: The energy band gaps, refractive index and optical transmittance of Ag₂O₃ nanostructures.

Laser Fluency (J/cm ²)	Film Thickness (nm)	E _g measured (eV)	n measured	T %
43	340	3.47	1.31	90
57	325	3.45	1.24	87

The photoluminescence of the deposited Ag₂O₃ nanofilms are grown on the glass substrate for 150 °C are presented in Fig. 6. One emission band at 355 nm (3.47 eV) and 362 nm (3.45 eV) for different laser fluency could be observed. The peak 355 nm is the more intense than the 362 nm. It could be shown that the photoluminescence spectra have a strong UV emission zone, relating to high crystallization with ideal energy gap compared with the experimental data. Moreover, the relative intensity of the peaks also depends

on the corresponding irradiative recombination efficiency. The obtained read shift was related to the reduction in the deposited material grain size. Thus, the photoluminescence spectra of Ag₂O₃ prove that the material produced has sufficient quality for use in research of the optoelectronic devices.

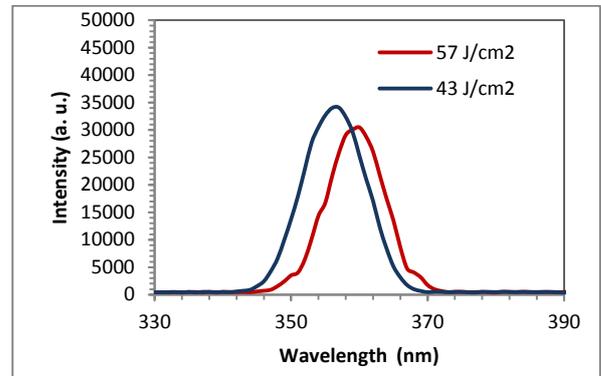


Figure (6), the photoluminescence of Ag₂O₃

3. CONCLUSION

Ag₂O₃ nanostructures have been prepared using PLD technique. It was found an approximate match between the value of the energy band gap that calculated by UV and PL. The maximum value of the transmission was found to be about 90%. The value of the refractive index showed the highest value of 1.24, while 1.31 that is appropriate for optoelectronic applications.

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